

**EXPEDITED PROCEDURE**  
**Examining Group Number 2800**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant:	Craig K. Carlson-Stevermer	Examiner:	Jermele M. Hollington
Serial No.:	10/622,849	Group Art Unit:	2829
Filed:	July 18, 2003	Docket No.:	A126.114.102
<b>Due Date:</b>	<b>February 22, 2007</b>		
Title:	WAFER STAGING PLATFORM FOR A WAFER INSPECTION SYSTEM		

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**AMENDMENT AND RESPONSE UNDER 37 C.F.R. 1.116**

**Mail Stop AF**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

This is responsive to the Final Office Action mailed November 22, 2006. Please amend the above-identified patent application as follows: